

Fig. 1(A)

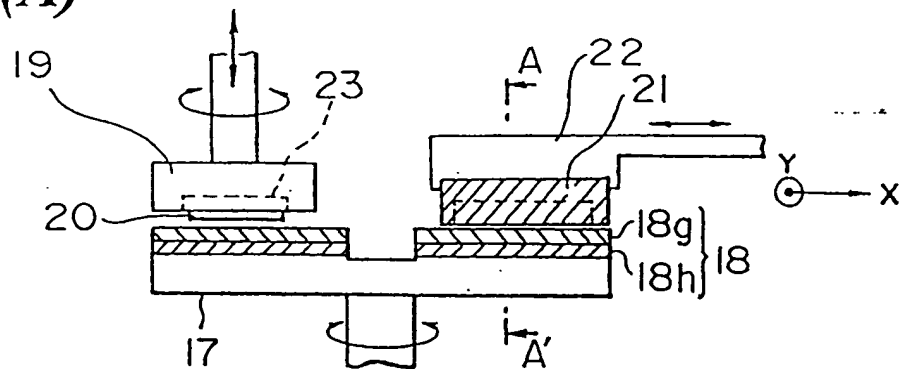


Fig. 1(B)

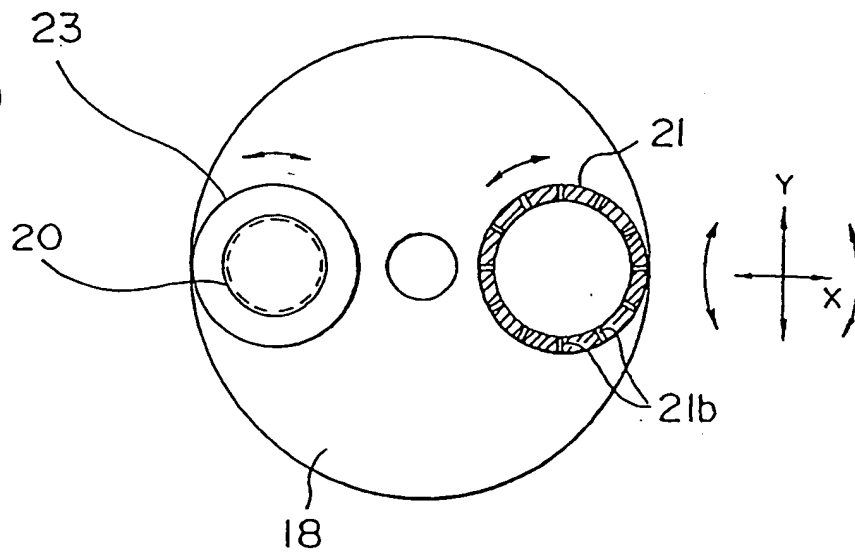
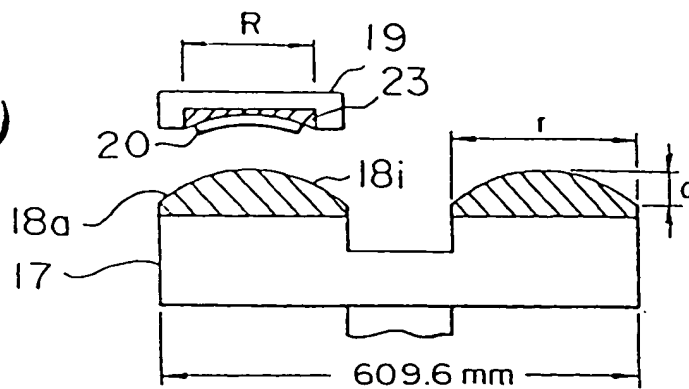


Fig. 2(A)



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Fig. 2(B)

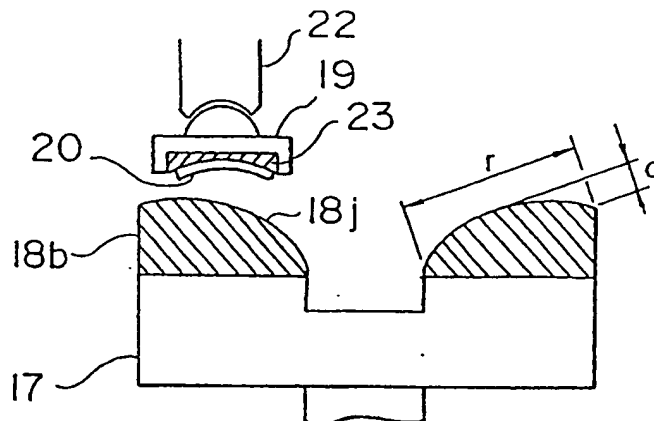
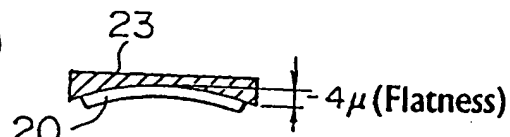


Fig. 2(C)



Wafer 6 inch ϕ ,
($r \approx 280$ mm, Flatness 4μ Incase of $d = 4 + 8\mu$)

Fig. 2(D)



Fig. 2(E)



Fig. 3

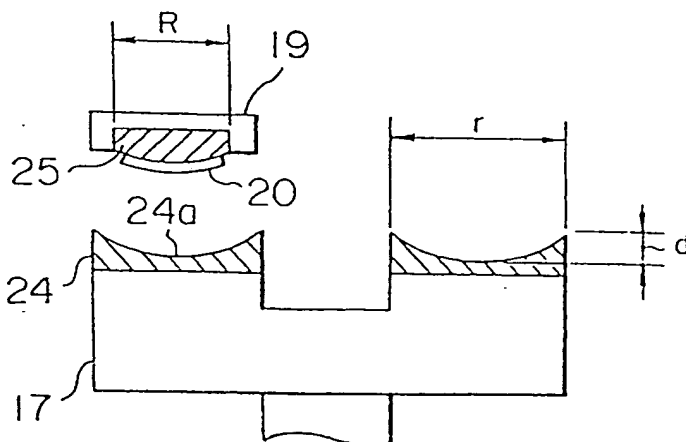


Fig. 4(A)

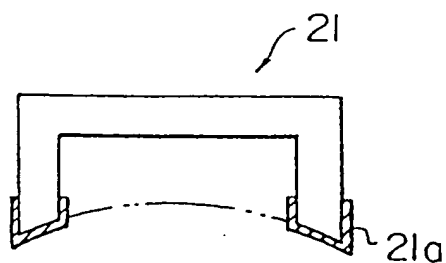


Fig. 4(B)

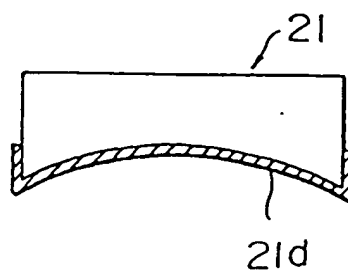
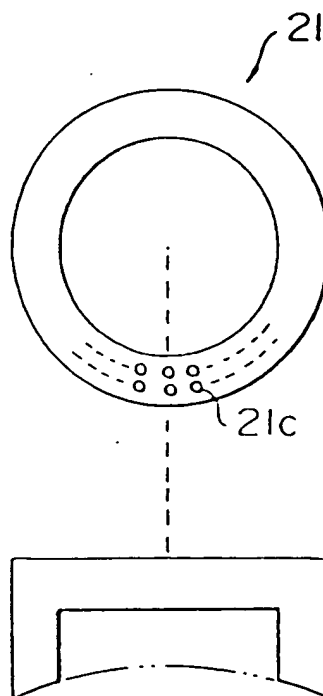


Fig. 4(C)



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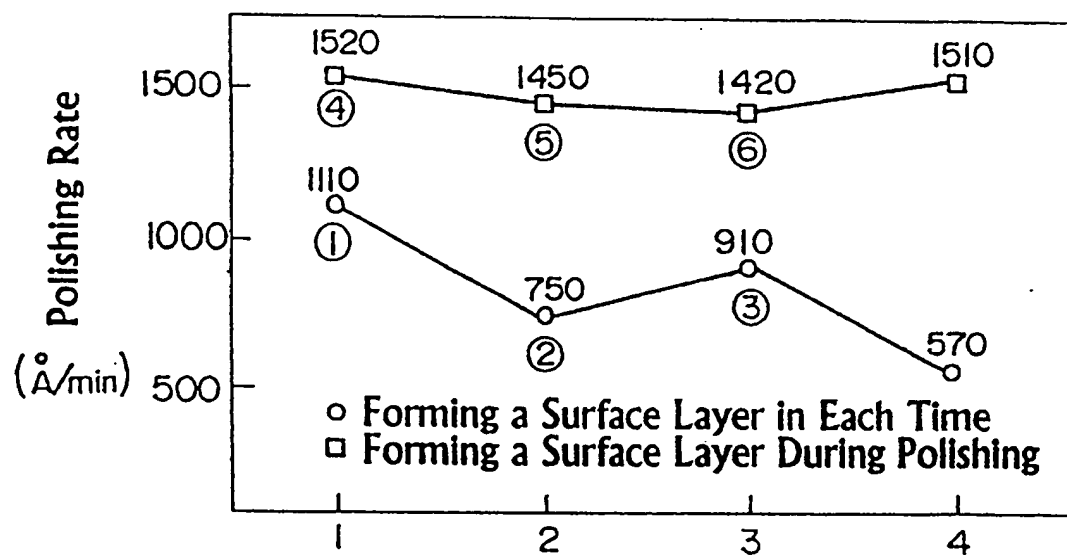
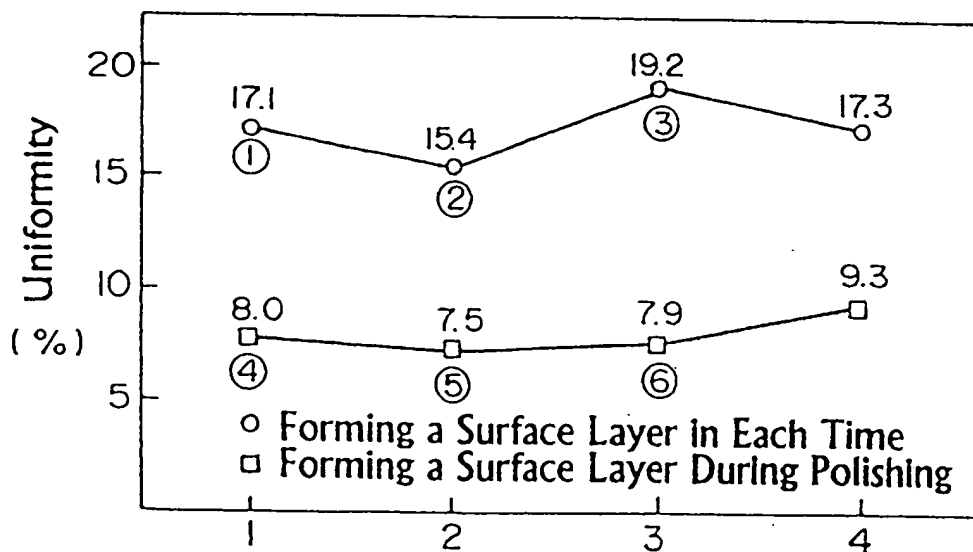
Fig. 5*Fig. 6*

Fig. 7

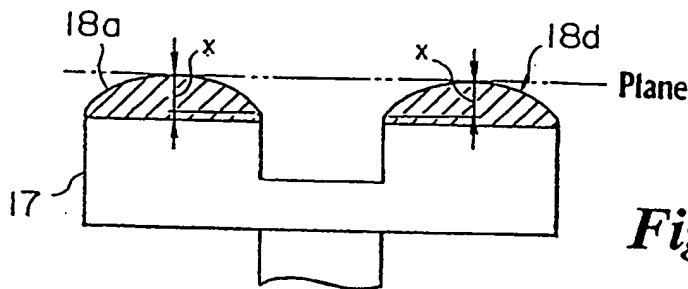
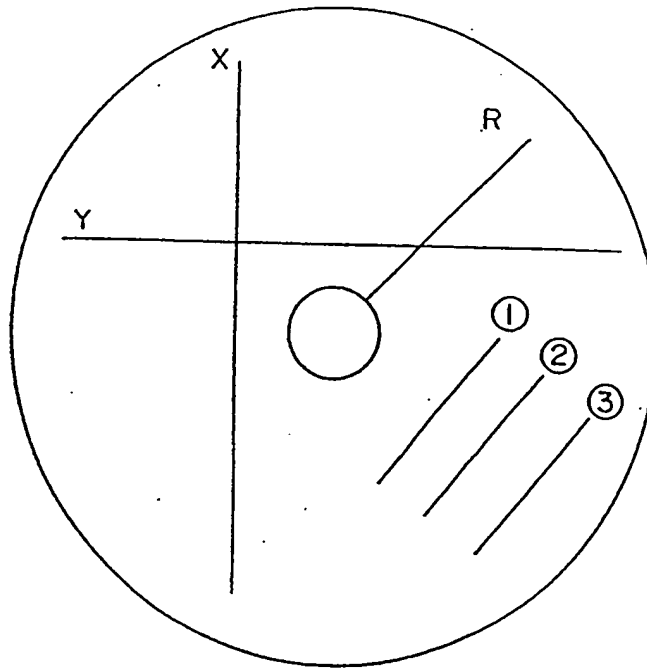


Fig. 8(A)

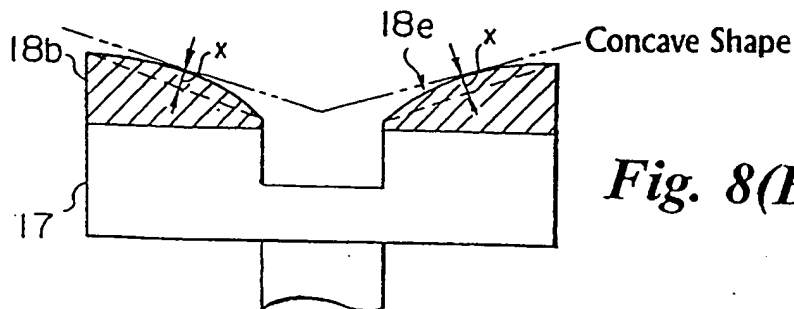


Fig. 8(B)

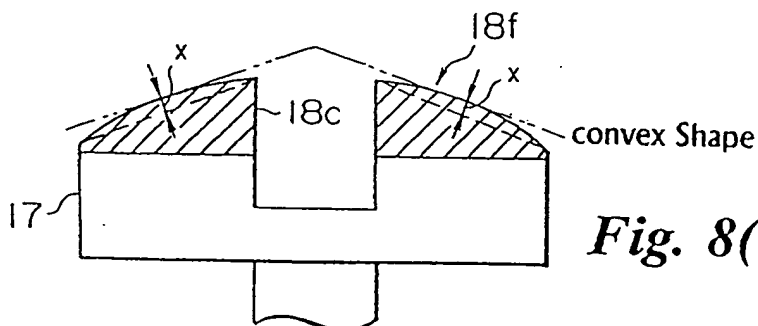
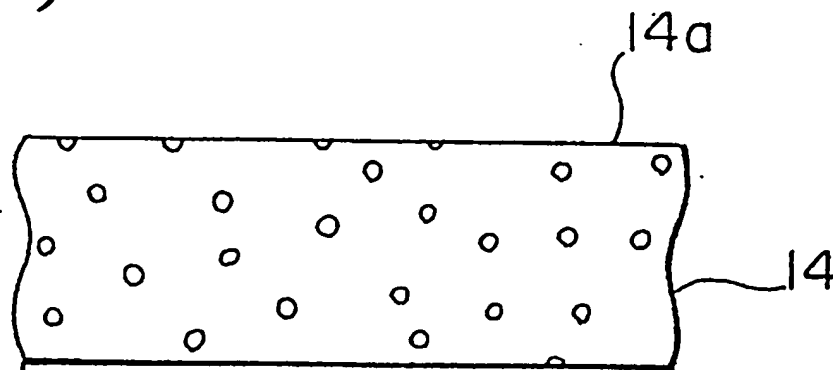
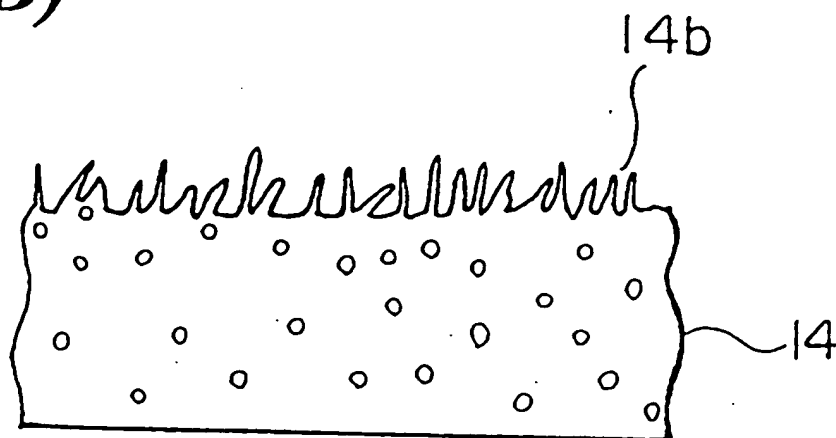


Fig. 8(C)

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Fig. 9(A)*Fig. 9(B)*

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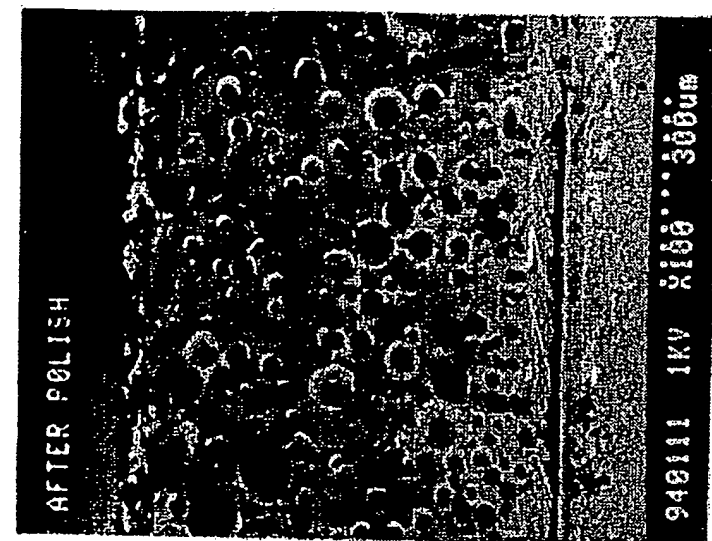


FIG. 12

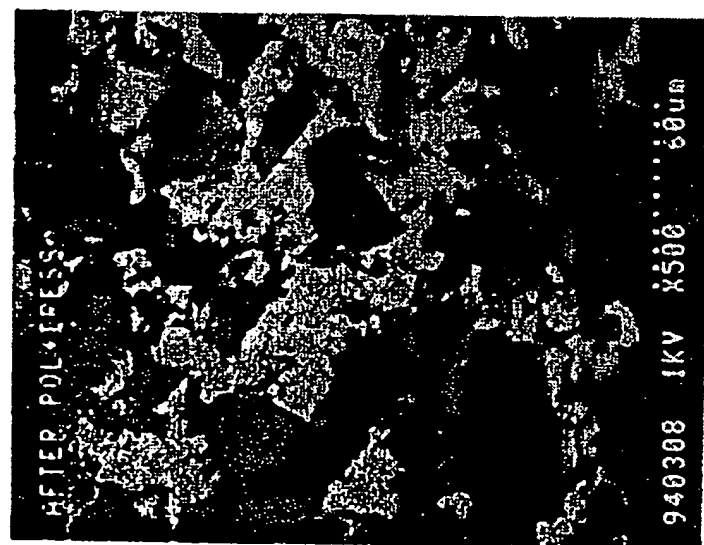


FIG. 11

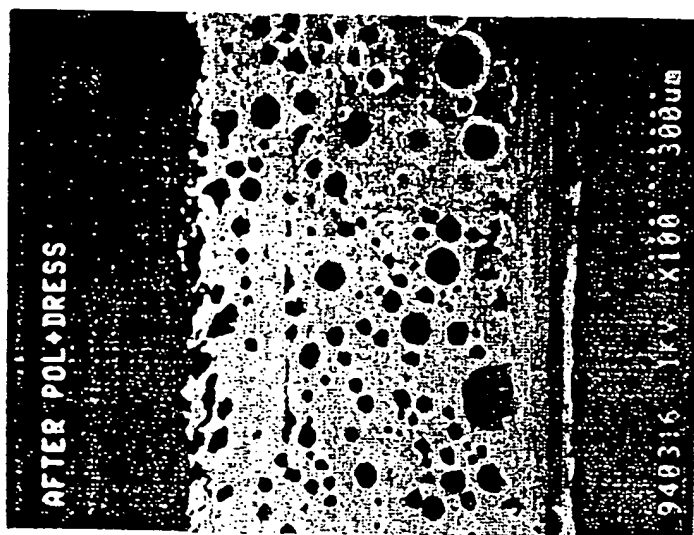


FIG. 10

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FIG.13

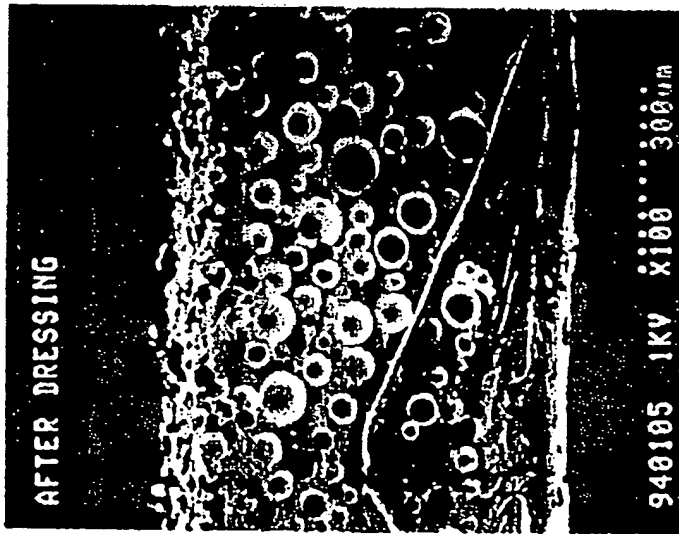


FIG.14

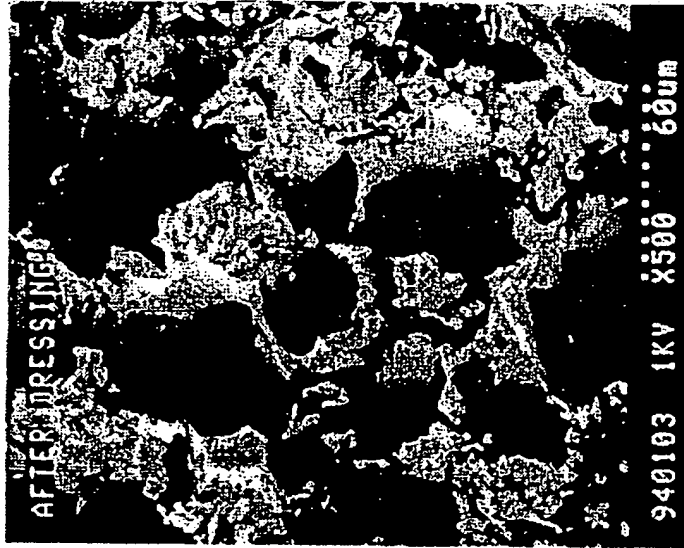


FIG.15

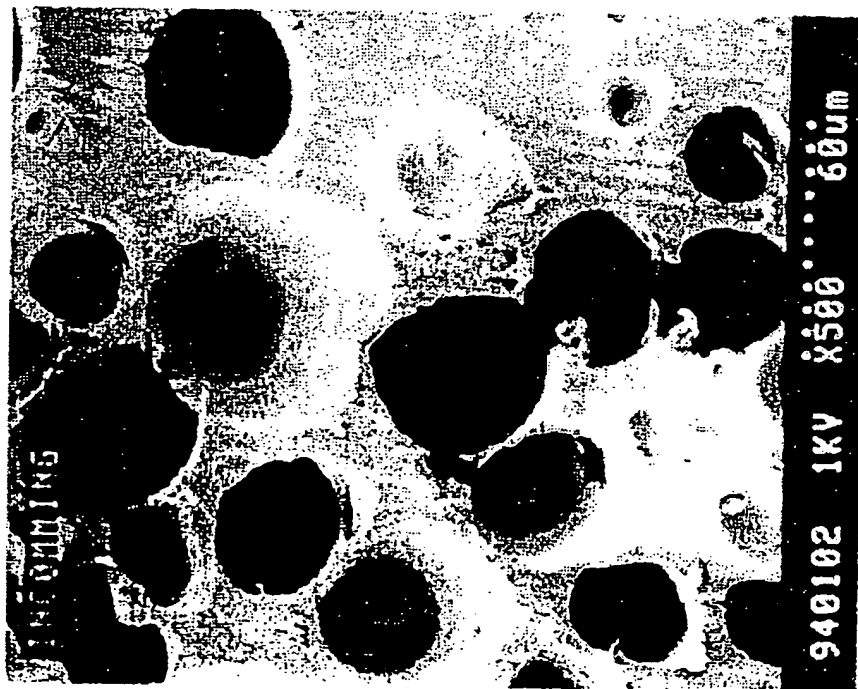


FIG. 17

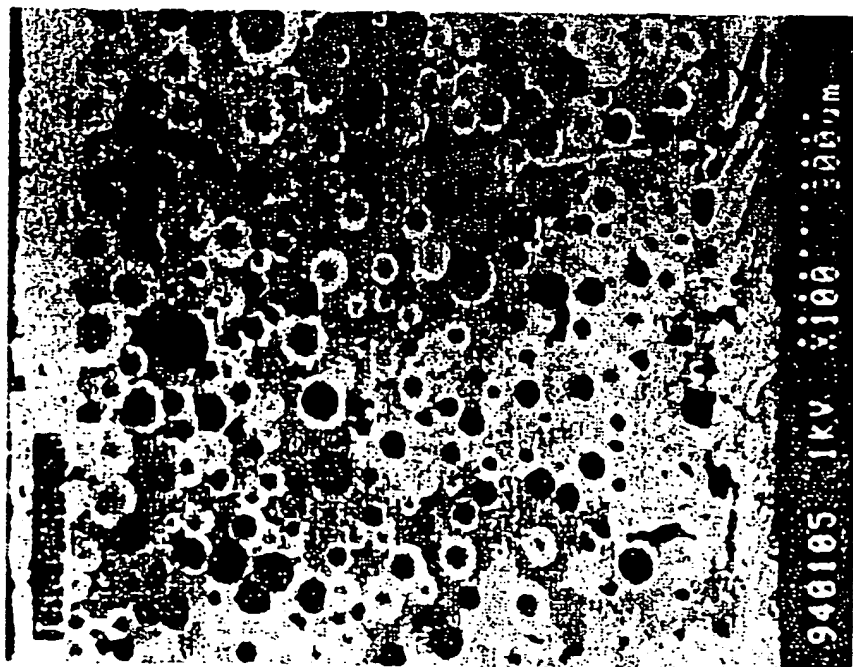


FIG. 16

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Fig. 18

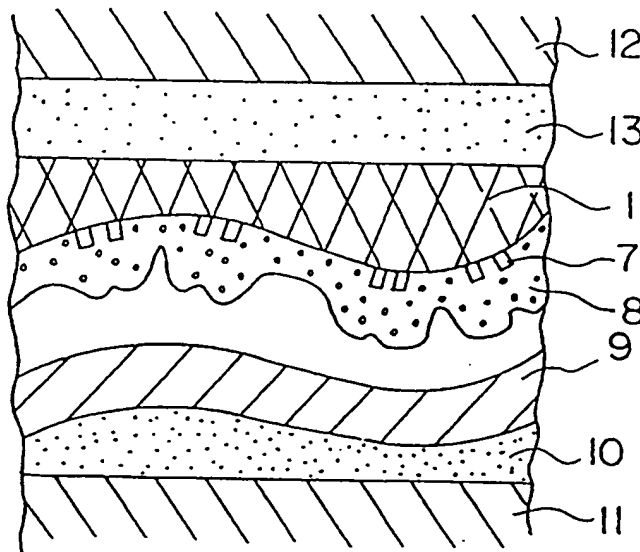


Fig. 19

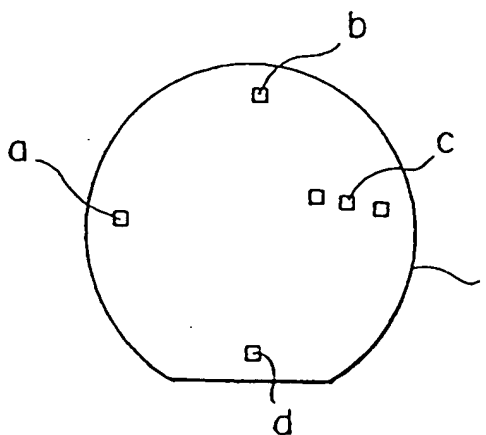
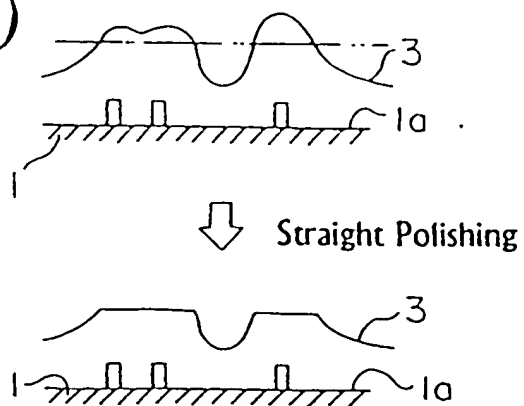


Fig. 20(A)



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Fig. 20(B)

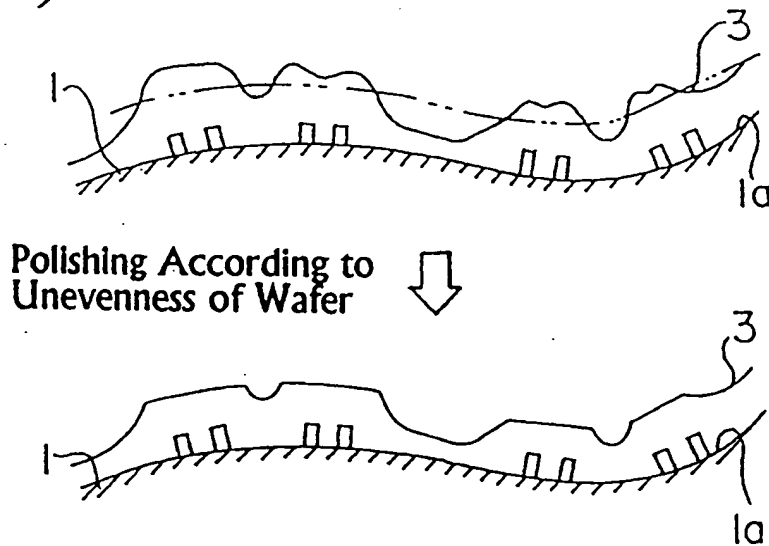


Fig. 21(A)

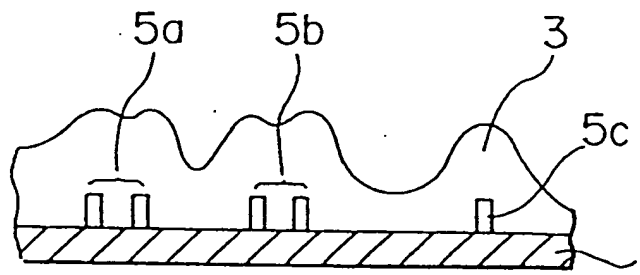
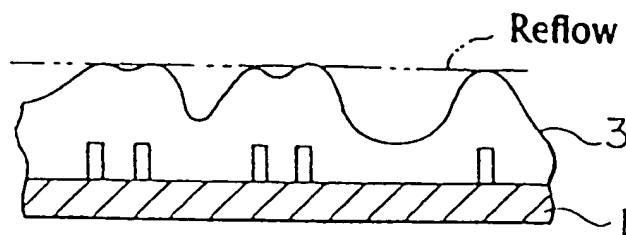
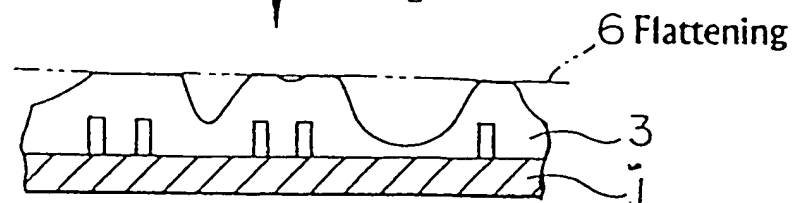


Fig. 21(B)



Etching

Fig. 21(C)



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Fig. 22(A)

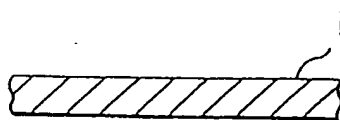


Fig. 22(B)

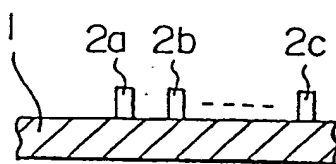


Fig. 22(C)

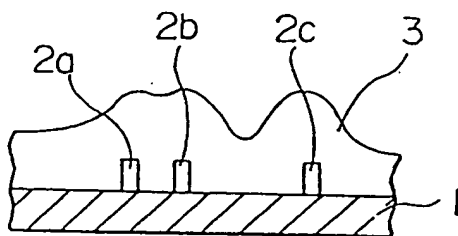


Fig. 22(D)

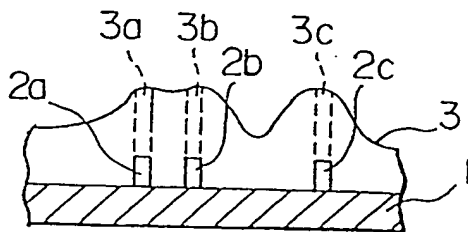
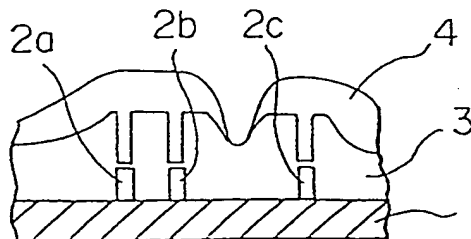


Fig. 22(E)



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